



IFW 2822 \$
Attorney's Docket No. 42390P5778D

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Krishna Seshan et al.

Application No. 10/013,103

Filed: November 6, 2001

For: **Semiconductor Passivation Deposition Process
for Interfacial Adhesion**

Examiner: Lewis, Monica

Art Unit: 2822

AMENDMENT AND RESPONSE TO OFFICE ACTION

Mail Stop Amendment
Commissioner for Patents
P. O. 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed August 24, 2005, regarding the above referenced application, Applicants respectfully request entry of the amendments set forth below and consideration of the remarks that follow.